AF/1762

PATENT HATMAN

AITY, Dkl. No. AMAT/5027/CP/I/COPPERPLS

ATT

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Chen, et al.

Serial No.: 10/052,049

Confirmation No.: 1518

Filed:

January 16, 2002

For:

Method for Growing Thin Films by Catalytic

Enhancement

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Examiner:

Group Art Unit: 1762

Timothy H. Meeks

CERTIFICATE OF MAILING 37 CFR 1.8

I hereby certify that this correspondence is being deposited on June 2, 2004 with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

6/2/04 Years ?
Date Signature

MAIL STOP AF Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

## **RESPONSE TO FINAL OFFICE ACTION DATED APRIL 8, 2004**

In response to the Final Office Action dated April 8, 2004, having a shortened statutory period for response set to expire on June 8, 2004, please enter this response and reconsider the claims pending in the application for reasons discussed below. The Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/5027/KMT, the amount of \$110.00, for a statutory disclaimer fee, along with any other fees to make this response timely and acceptable to the Office.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper. Remarks begin on page 6 of this paper.